Fig. 1

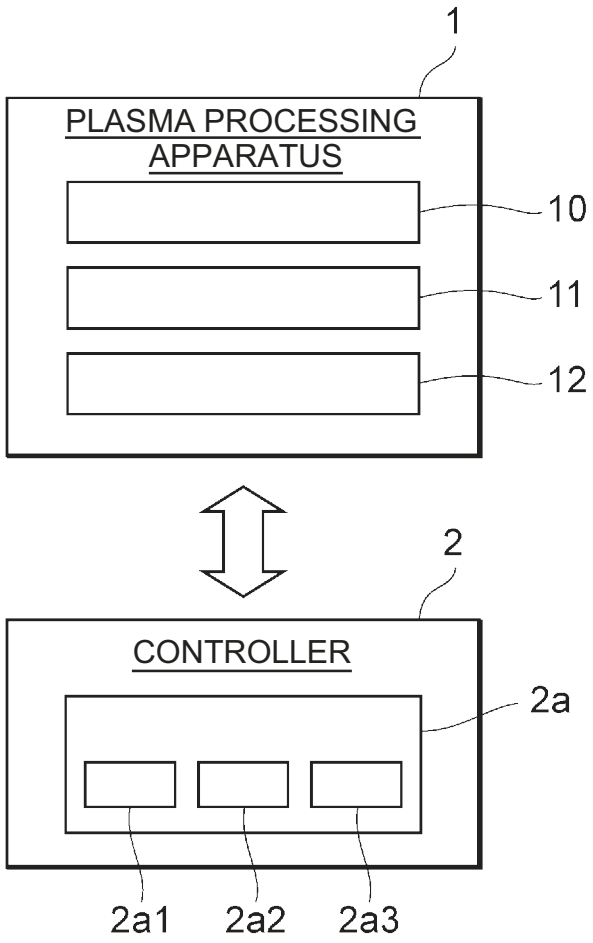

1
PLASMA PROCESSING APPARATUS
10
11
12
2
CONTROLLER
2a
2a1
2a2
2a3

Fig. 2

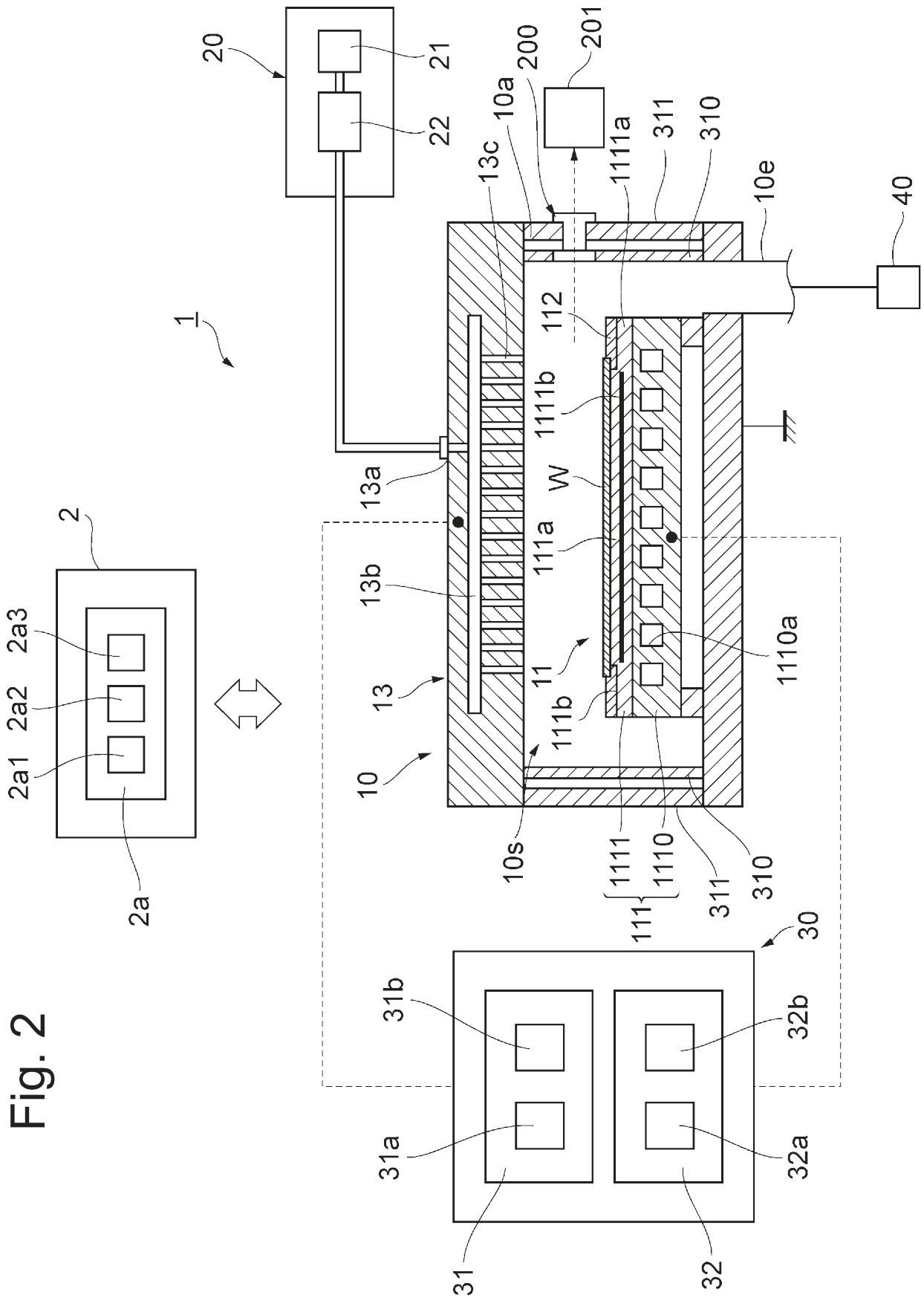
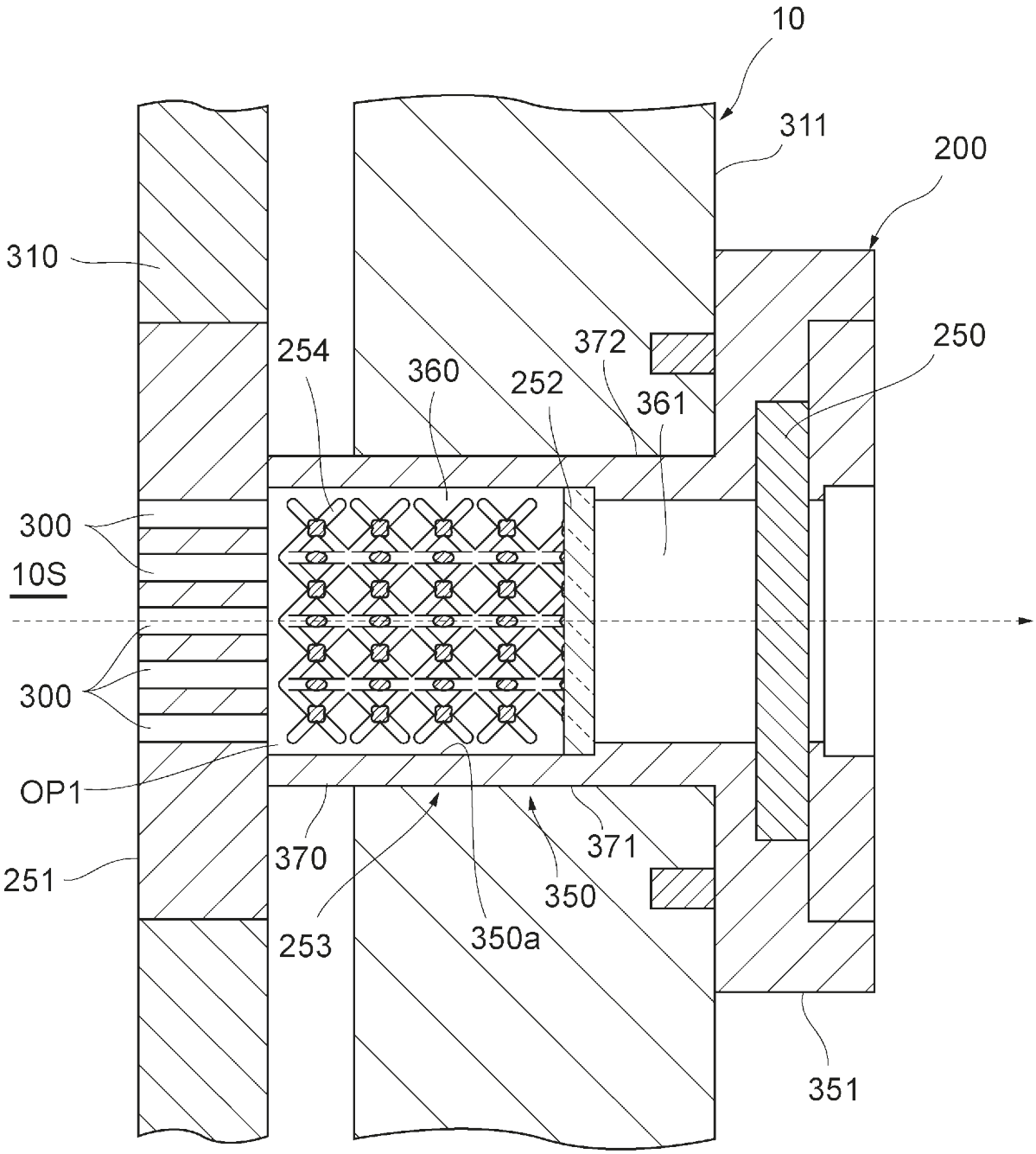

1
2
2a3
2a2
2a1
2a
20
21
22
200
201
10a
13c
1111a
311
310
10e
40
112
1111b
W
111a
13a
13b
13
11
1110a
111b
10
10s
1111
1110
111
311
310
30
31b
32b
31a
32a
31
32

Fig. 3


10
311
200
310
254
360
252
372
361
250
300
10S
300
OP1
251
370
253
350a
350
371
351

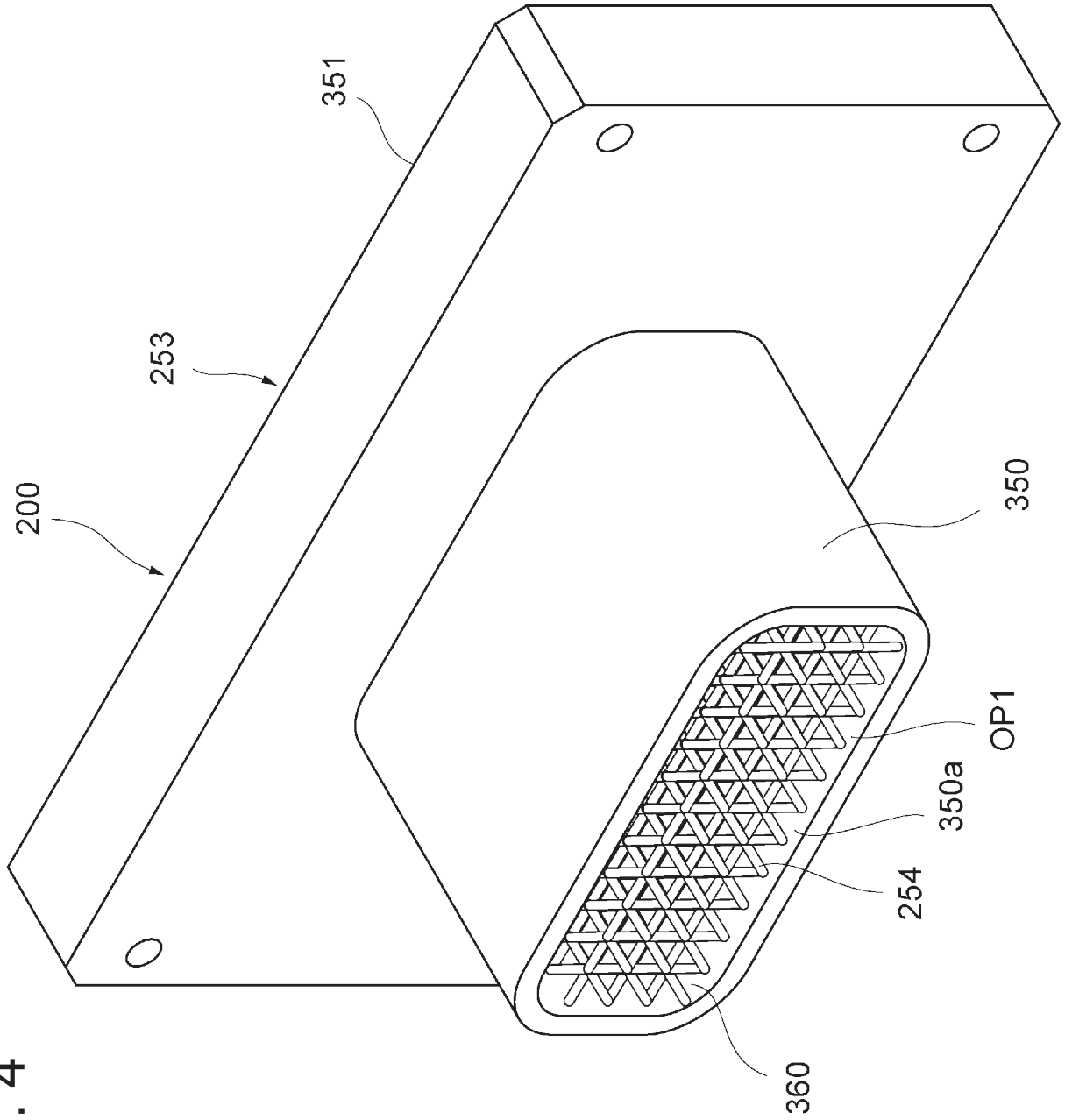


Fig. 4

Fig. 5

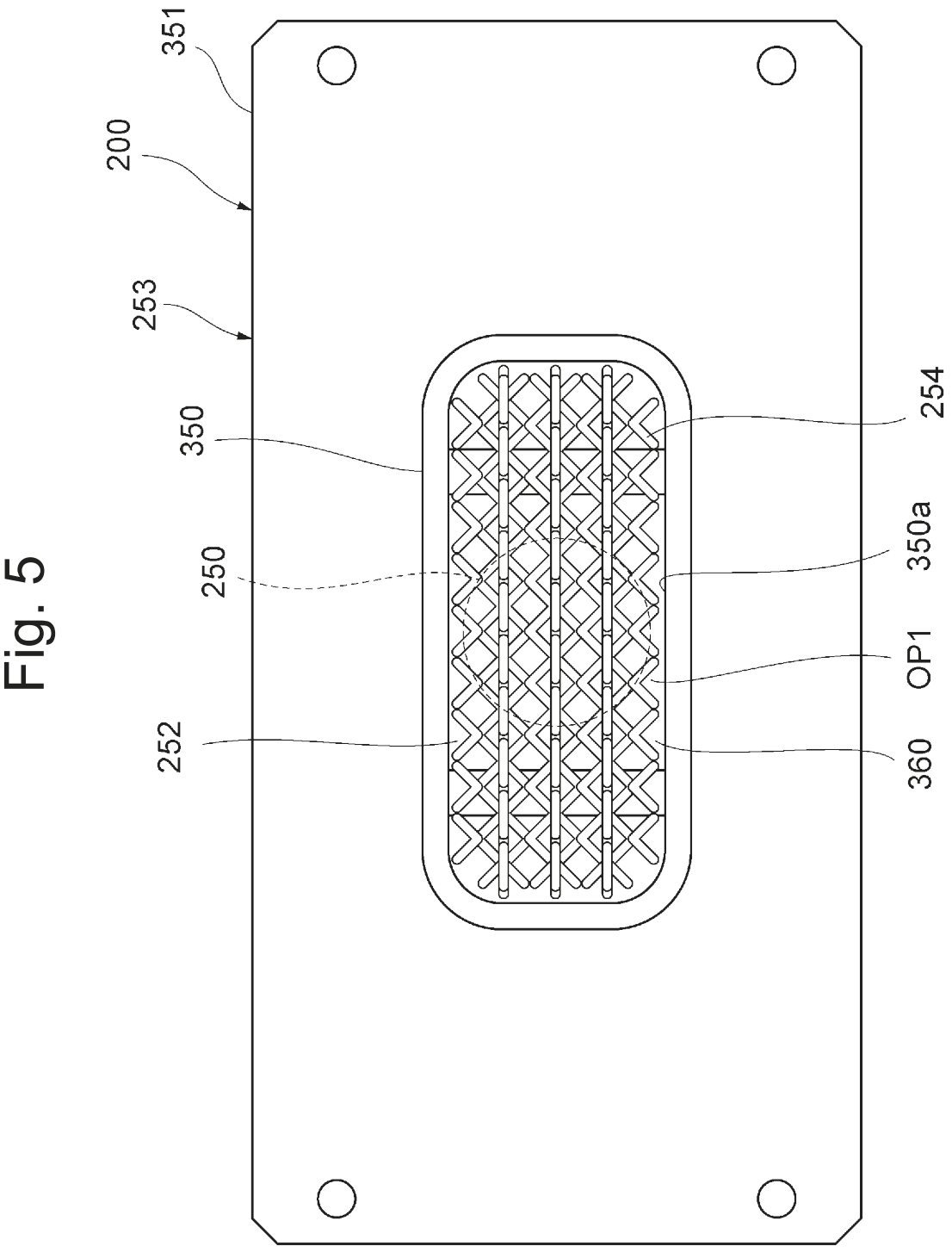


Fig. 6

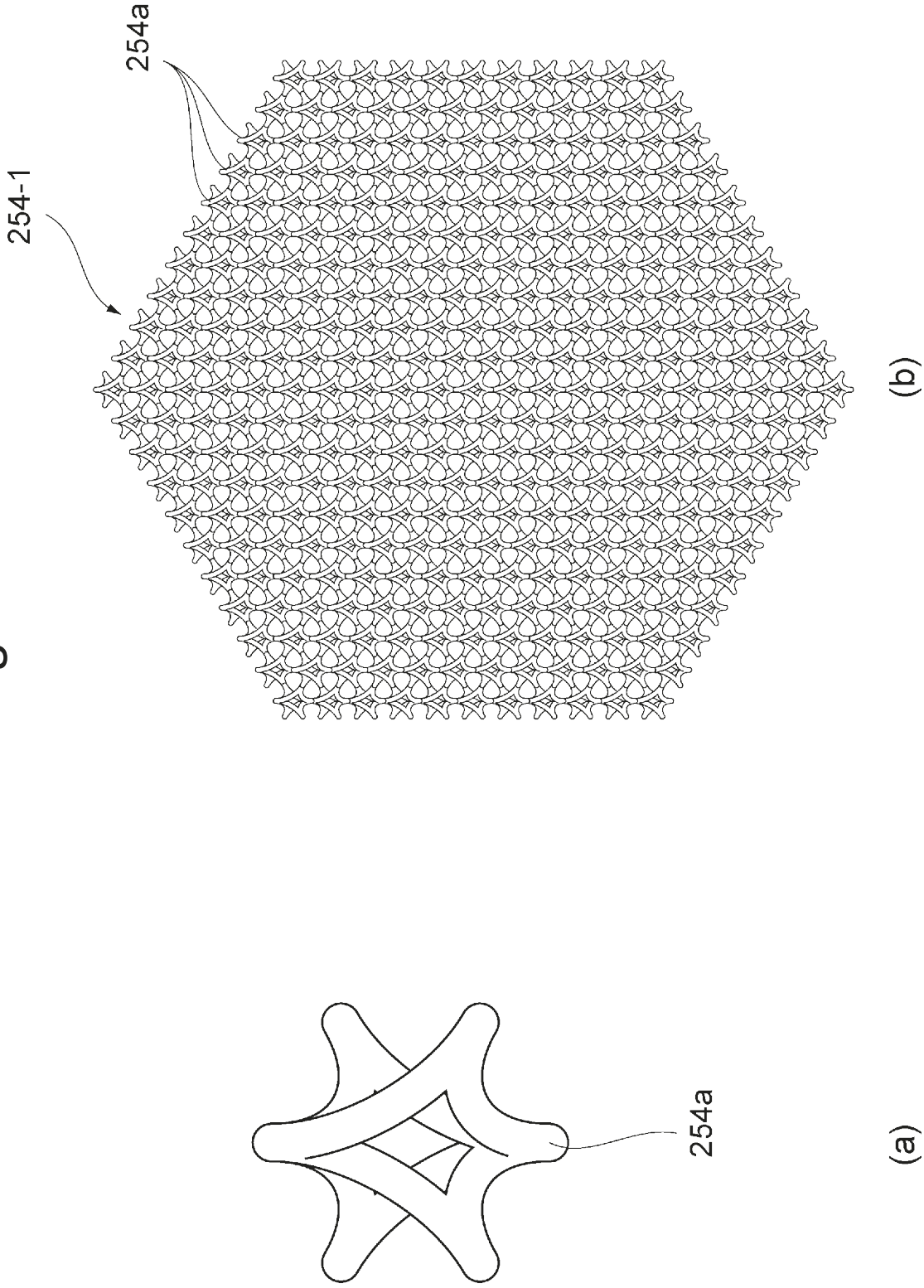
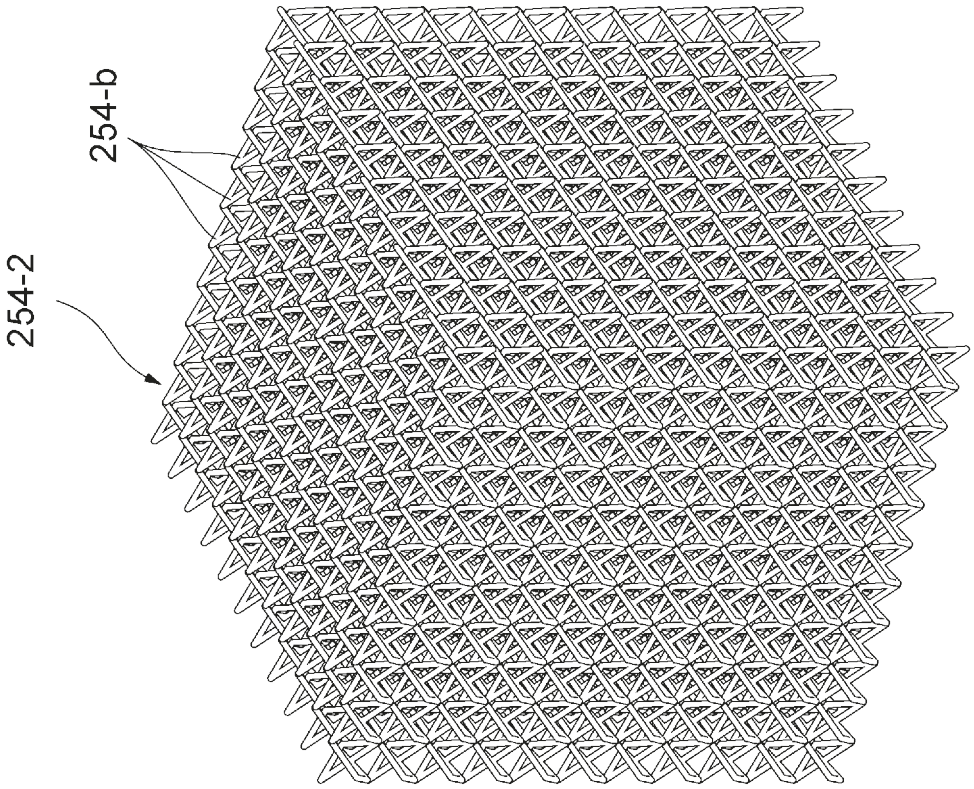
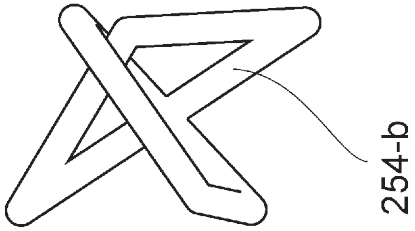


Fig. 7

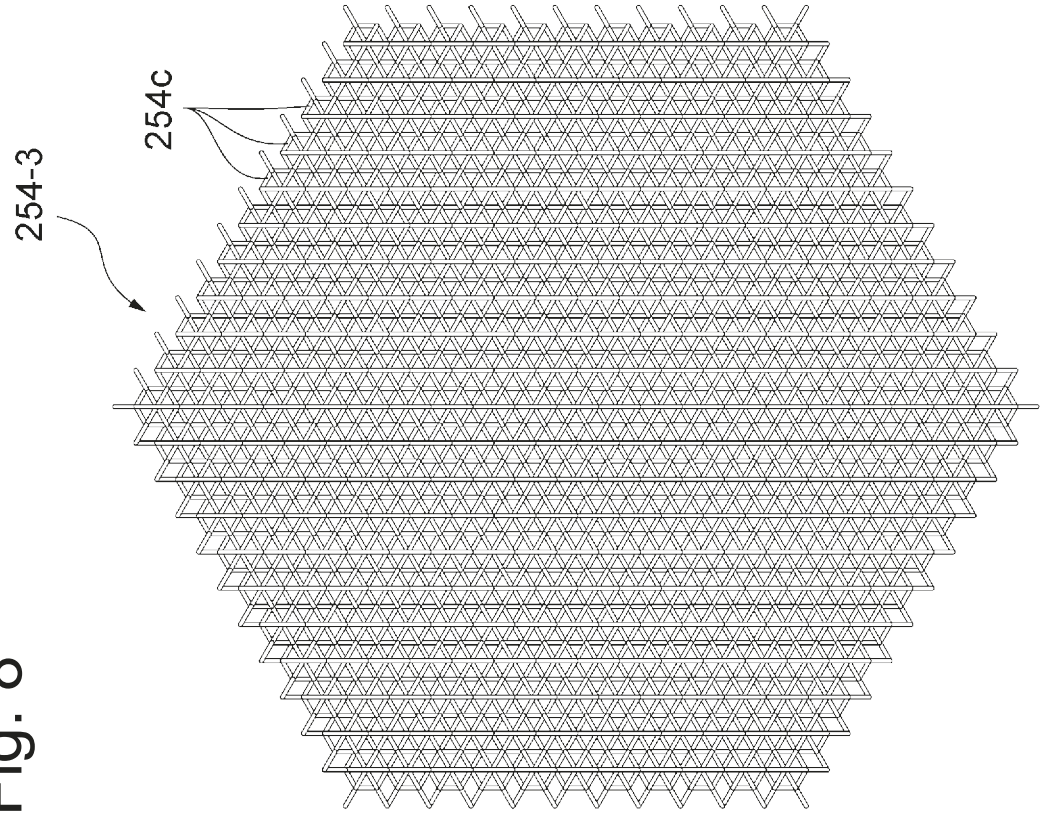


(b)



(a)

Fig. 8



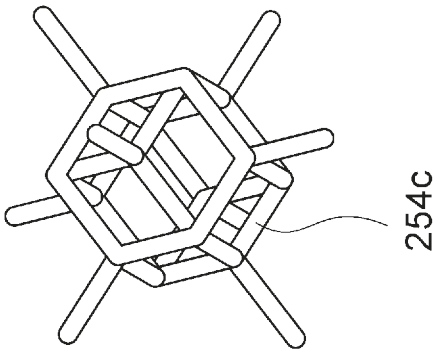


Fig. 9

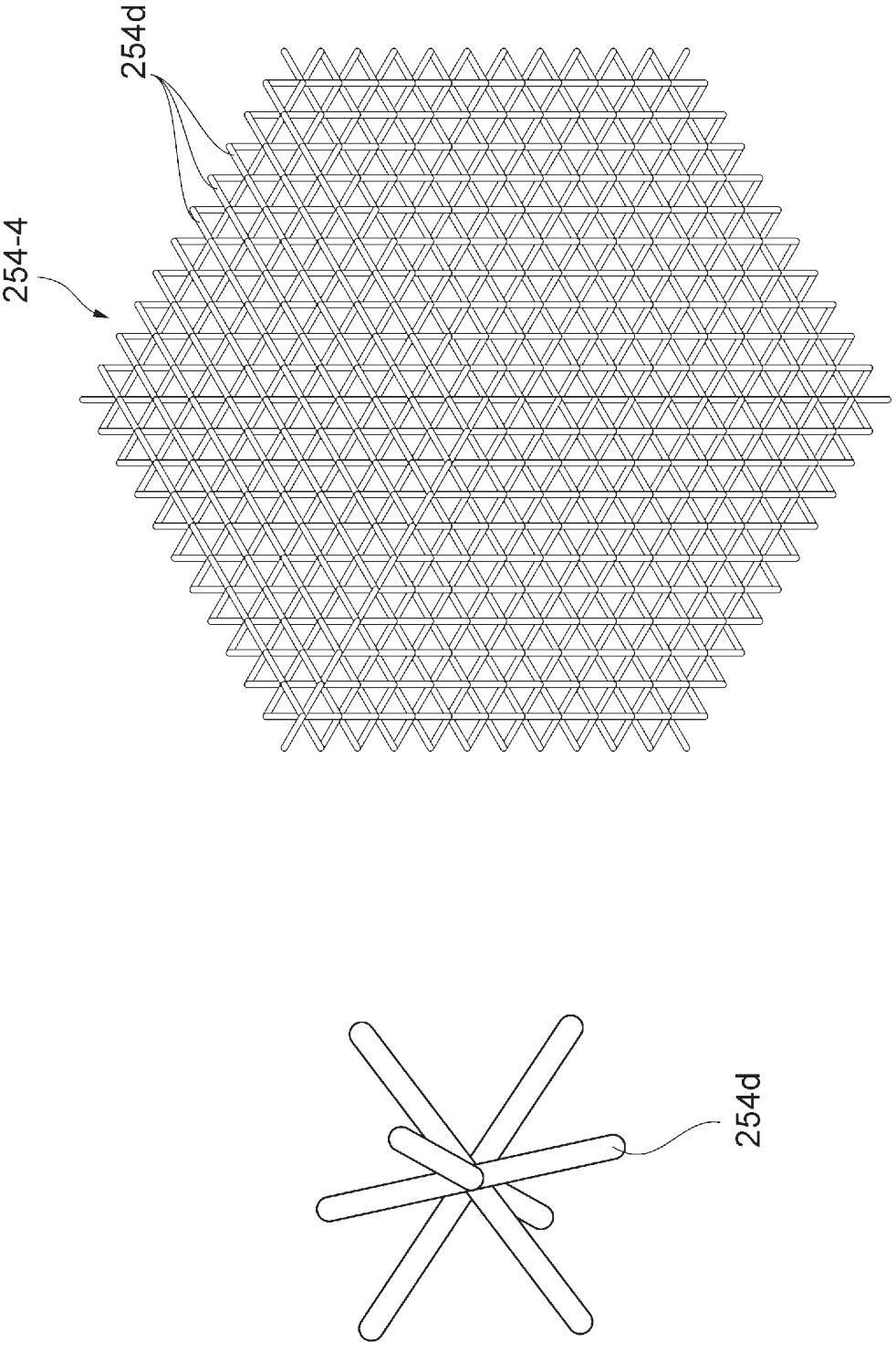


Fig. 10

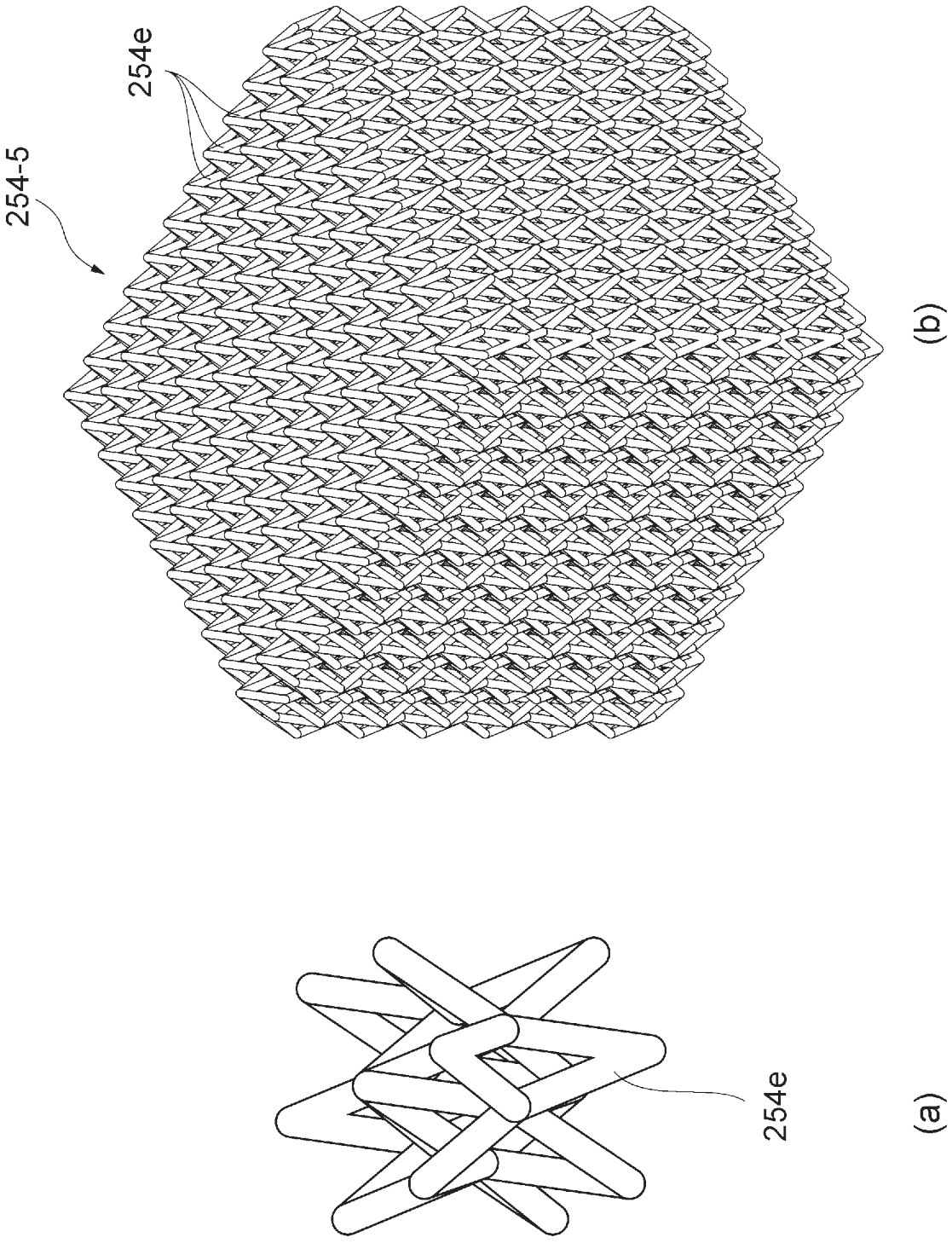
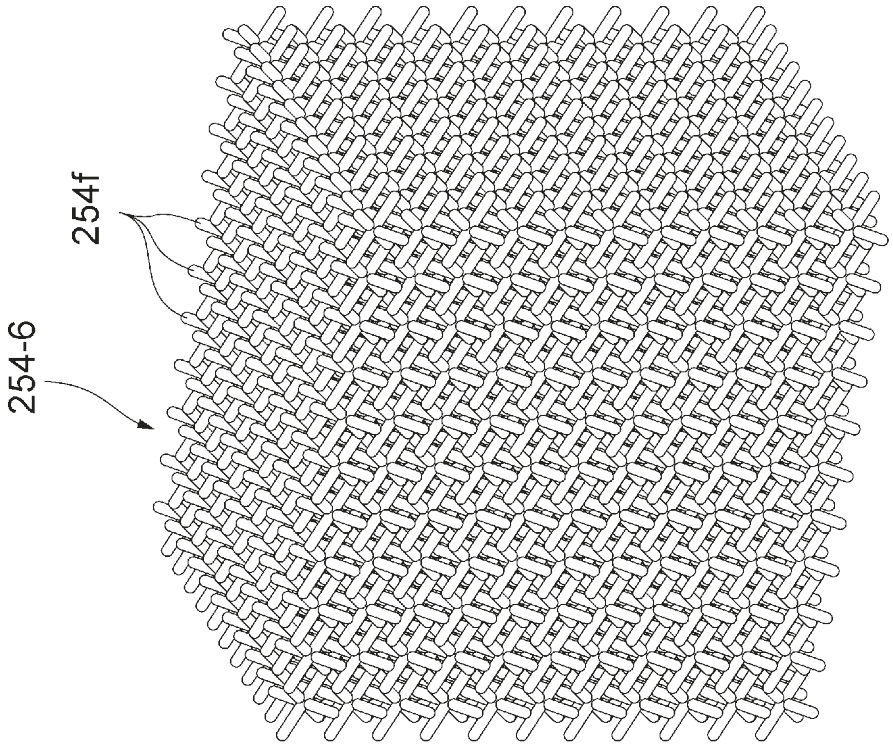
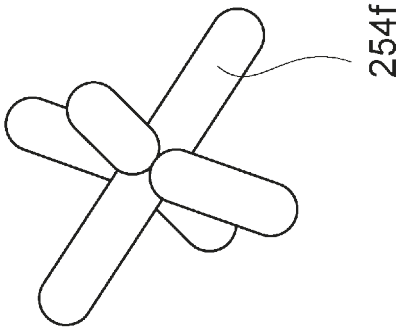


Fig. 11



(b)



(a)

Fig. 12

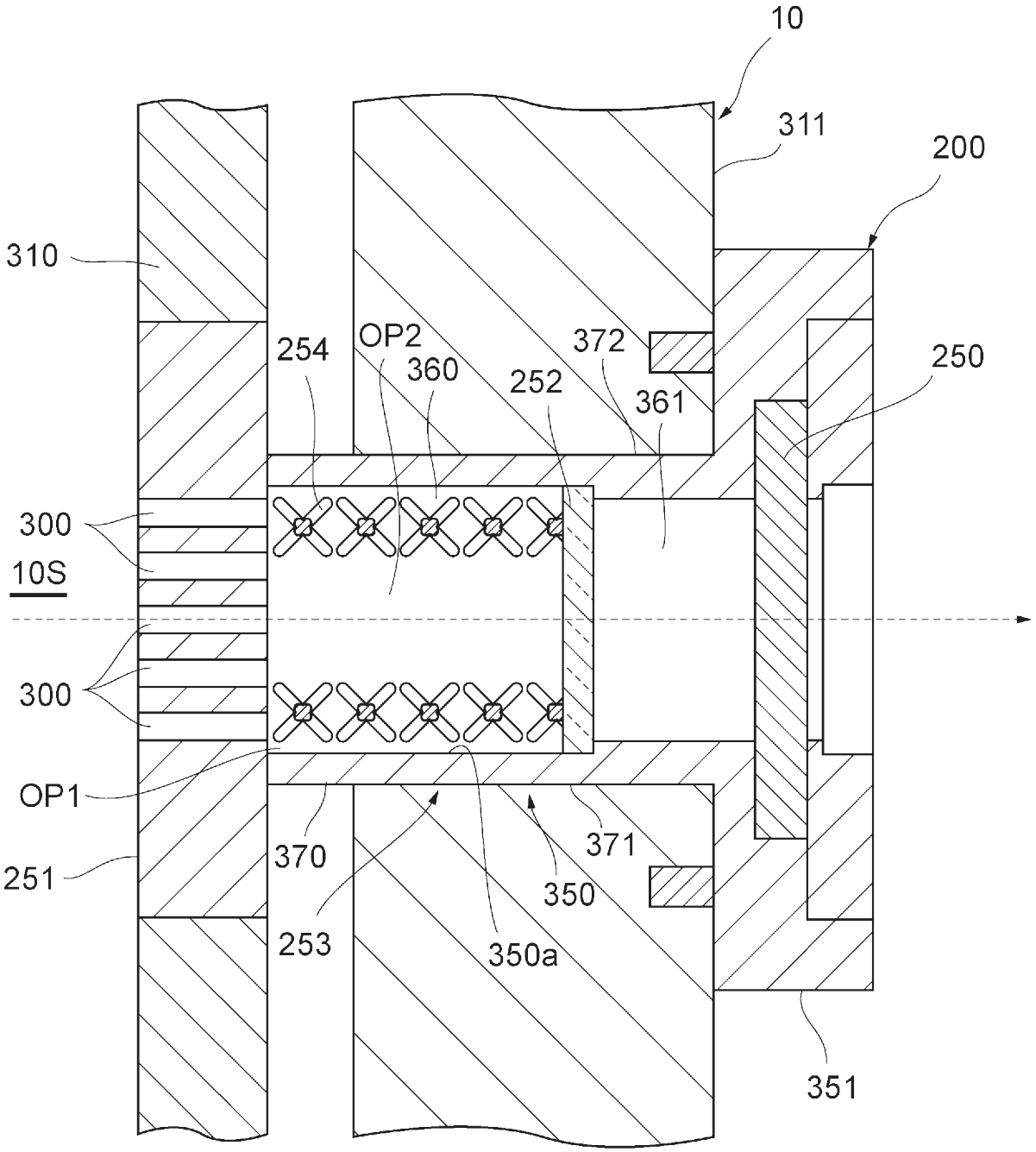

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Fig. 13

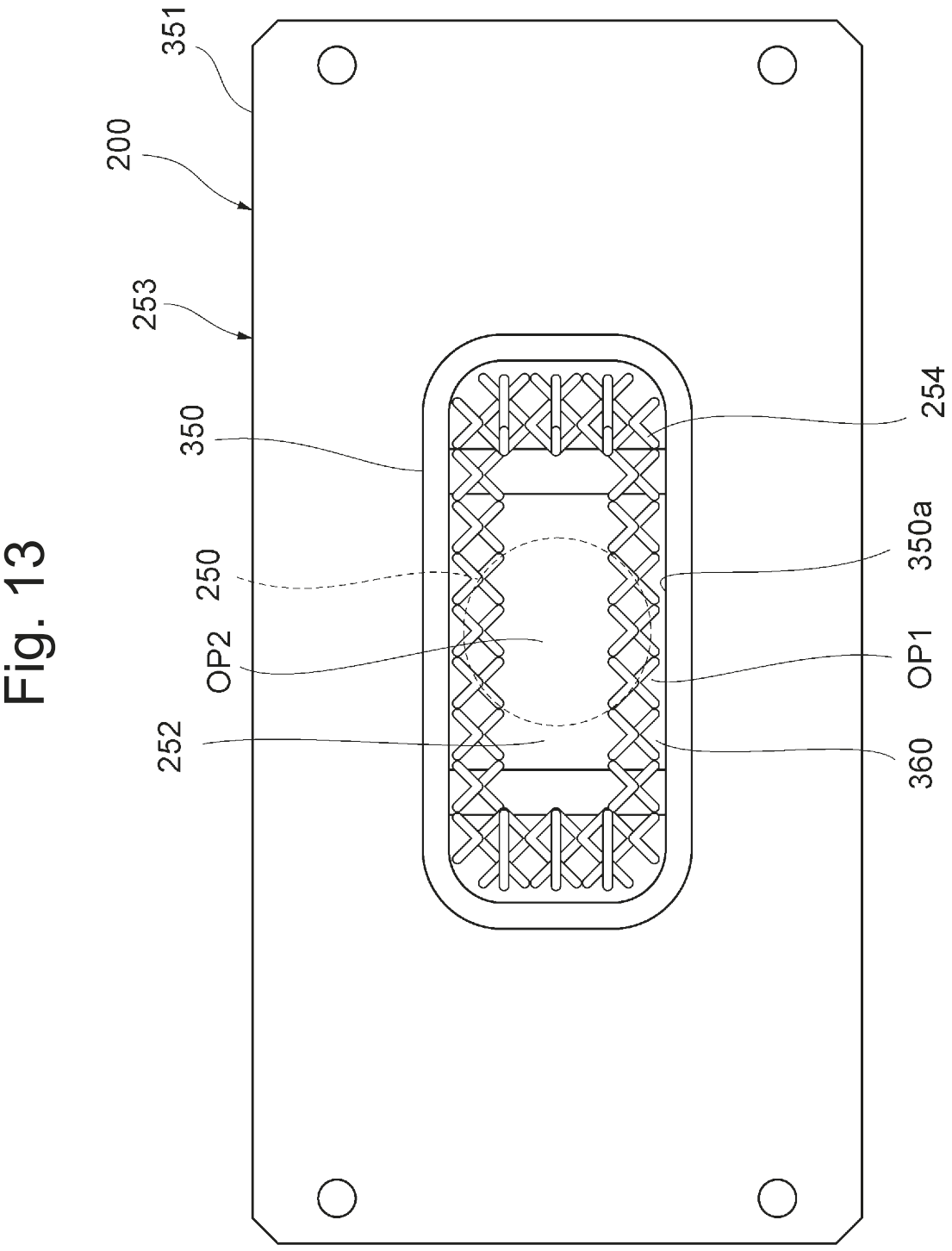
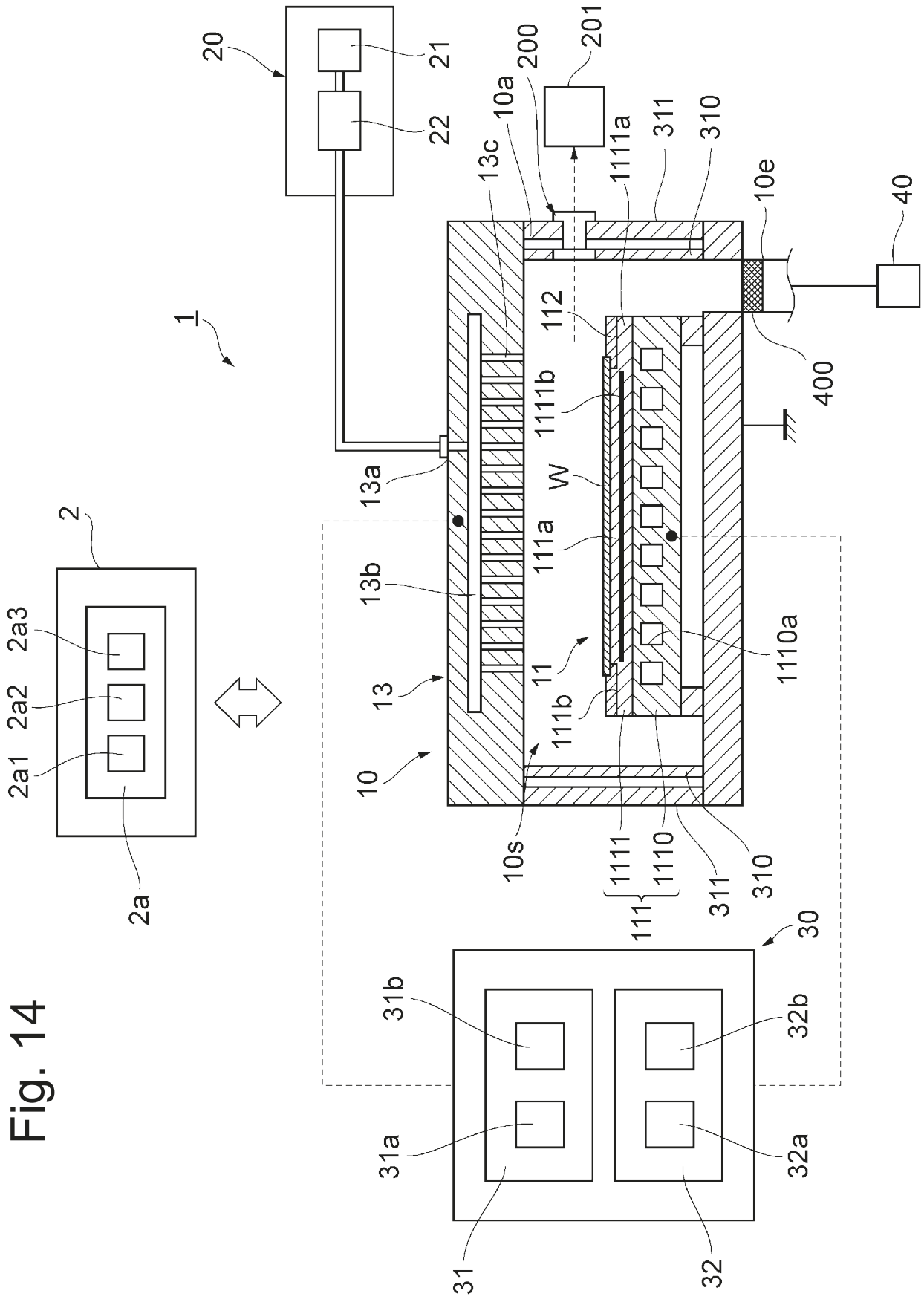


Fig. 14


1
2
2a3
2a2
2a1
2a
20
21
22
200
201
10a
13c
1111a
311
310
10e
40
400
112
1111b
W
111a
13a
13b
13
11
111b
10
1110a
10s
1111
1110
111
311
310
30
31b
32b
31a
32a
31
32